Exam.Code:0975 Sub. Code: 7105

## 2023

## M. Tech. (Micro-Electronics) First Semester MIC-102: Integrated Circuit Technology

Time allowed: 3 Hours Max. Marks: 50

**NOTE**: Attempt <u>five</u> questions in all, including Question No. I which is compulsory and selecting two questions from each Unit.

x-x-x

|      | ~~~~   |        |
|------|--|--------|
| I.   | Answer the following:-   |        |
|      | a) Point defects   |        |
|      | b) Diffusion   |        |
|      | c) Metal film deposition   |        |
|      | d) Name water cleaning techniques  |        |
|      | e) Oxidation   |        |
|      | f) Etching   |        |
|      | g) Name one MOS device fabrication.                                      |        |
|      | h) Twin well process   |        |
|      | i) One problem in CMOS process   |        |
|      | j) Regression  | (10x1) |
|      | UNIT - I   |        |
| II.  | Explain Chemical vapour deposition technique in detail                   | (10)   |
| III. | Differentiate between p-channel and n-channel. What is ion- Implantation | (10)   |
| IV.  | Explain oxidation diffusion and metallization process in detail.         | (10)   |
|      | <u>UNIT - II</u>   |        |
| V.   | Explain Bipolar and MOS device fabrication techniques.                   | (10)   |
| VI.  | Write the differences between p MOS and n MOS with CMOS Technologies.    | (10)   |
| VII. | Explain the following:-  |        |
|      | a) Dry and Wet Etching.  |        |
|      | b) Nonlinear Regression  |        |
|      | c) Linear model with nonzero Intercept                                   | (10)   |
|      |  |        |